#### RESPONSE UNDER 37 C.F.R. § 1.116 EXPEDITING PROCEDURE EXAMINING GROUP 2826

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To Examiner: Kevin Quinto

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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Cheng, et al.

Docket No.:

TSM03-0698

Serial No:

10/786,643

Art Unit:

2826

Date Filed:

February 25, 2004

Title:

Method and Structure for CMOS Devices with Stress Relaxed by Ion

Implantation of Carbon or Oxygen Containing Ions

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I hereby certify that the following papers are being transmitted by facsimile to the U.S. Patent and Trademark Office at 703-872-9306 on the date shown above:

- Certification of Facsimile Transmission (1 page)

- Response to Final Office Action Under 37 C.F.R. § 1.116 (6 pages)

Respectfully submitted,

Andy A. Betts Legal Assistant

Confirmation Respectfully Requested

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Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## Response To Final Office Action Under 37 C.F.R. § 1.116

Dear Sir:

Applicants respectfully submit the following amendments and remarks in response to the Examiner's Final Office Action dated March 25, 2004. They are believed to be a full and complete response to said Action and to place the application in a condition for allowance or to place the application in a better condition for appeal. Entry is respectfully requested.